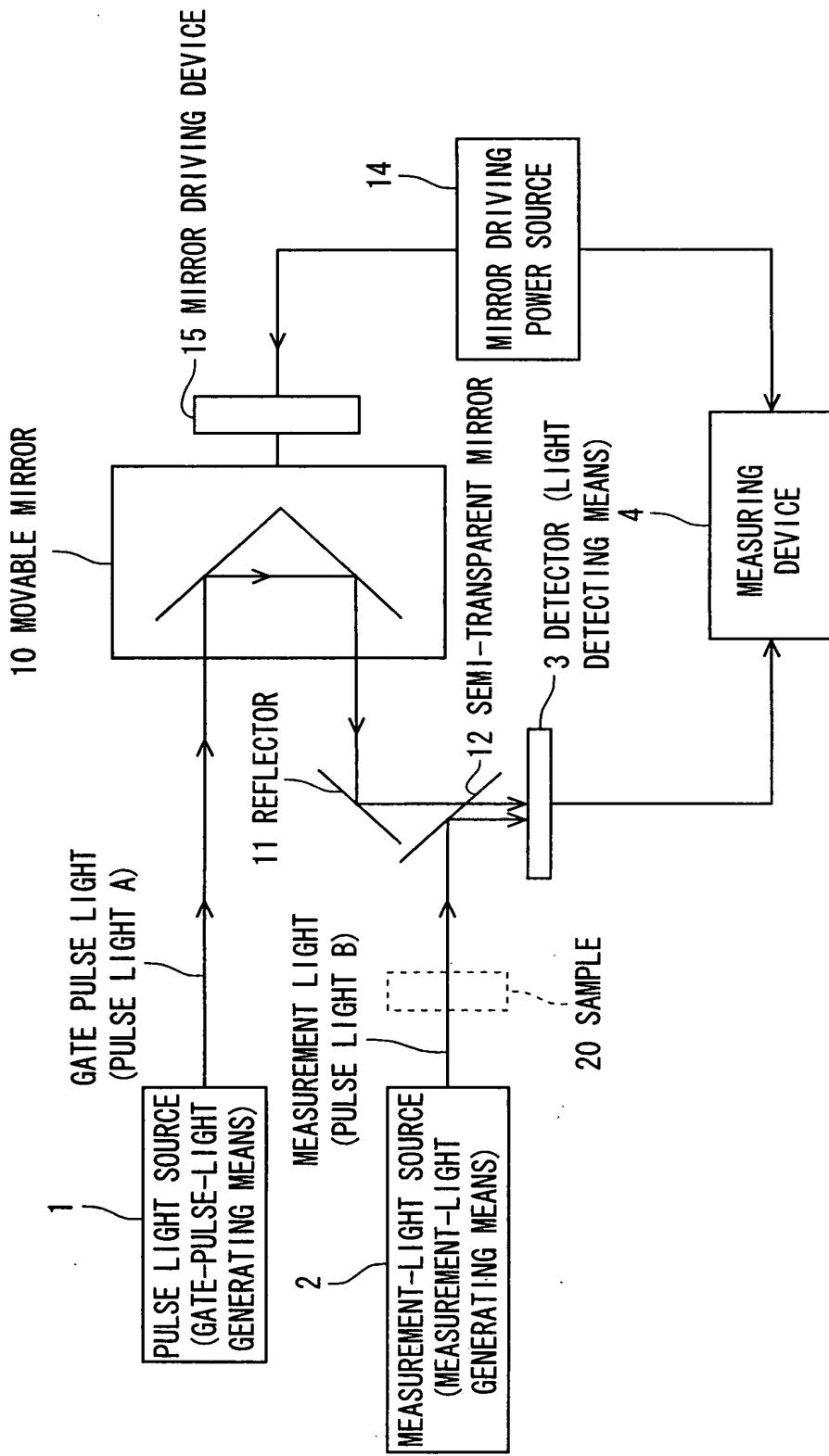


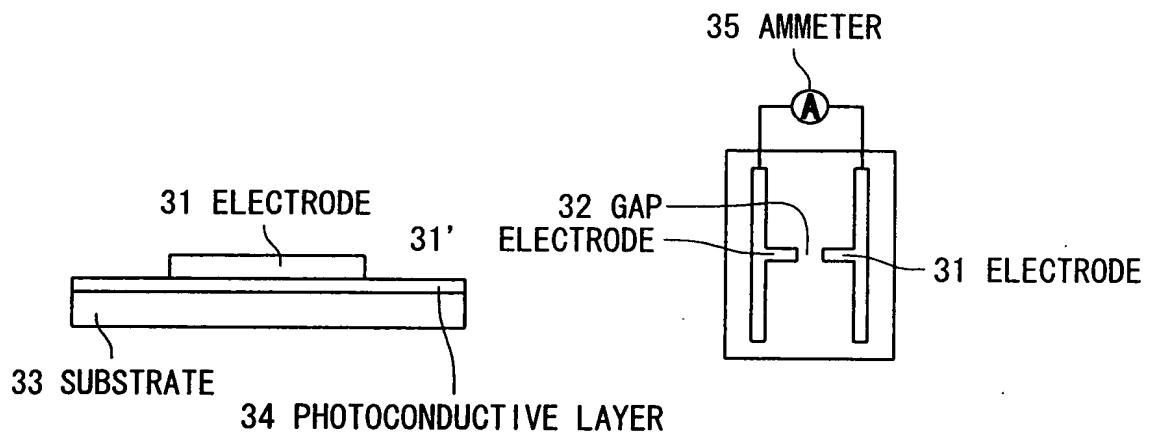
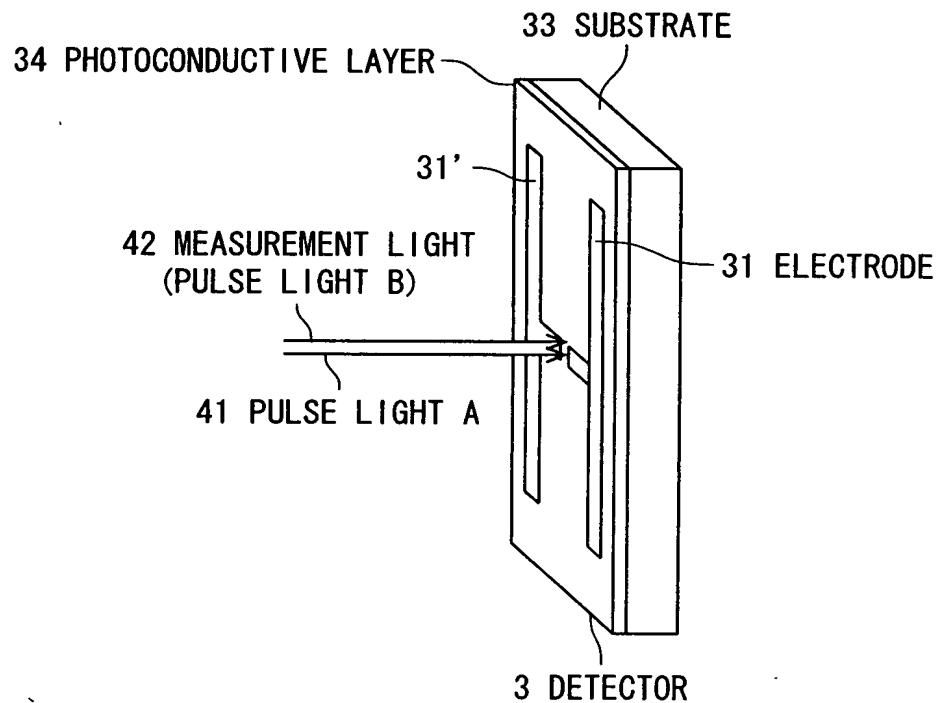
【図1】

FIRST EMBODIMENT OF THE INVENTION



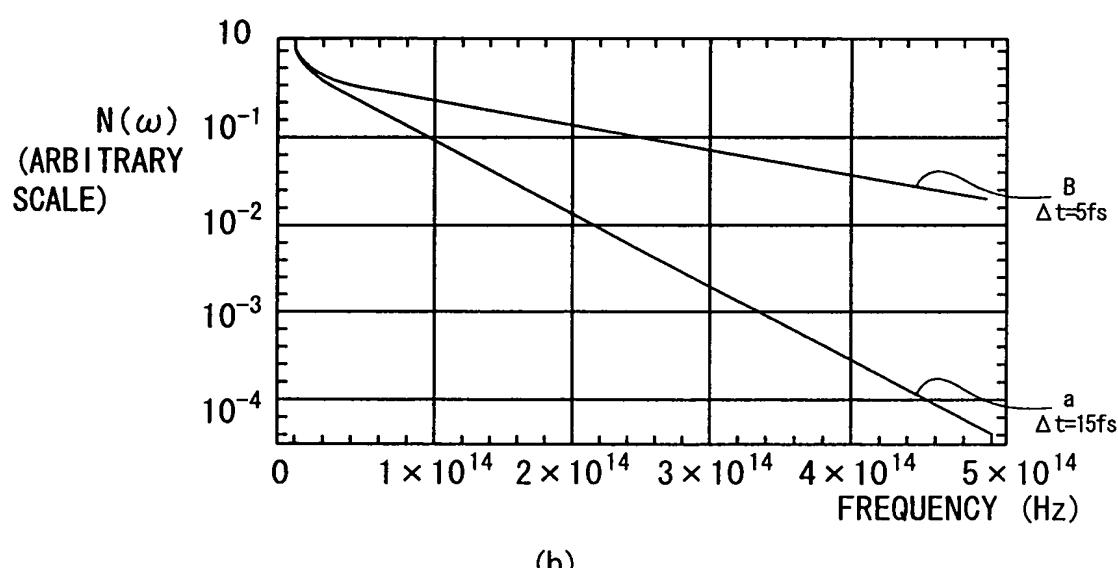
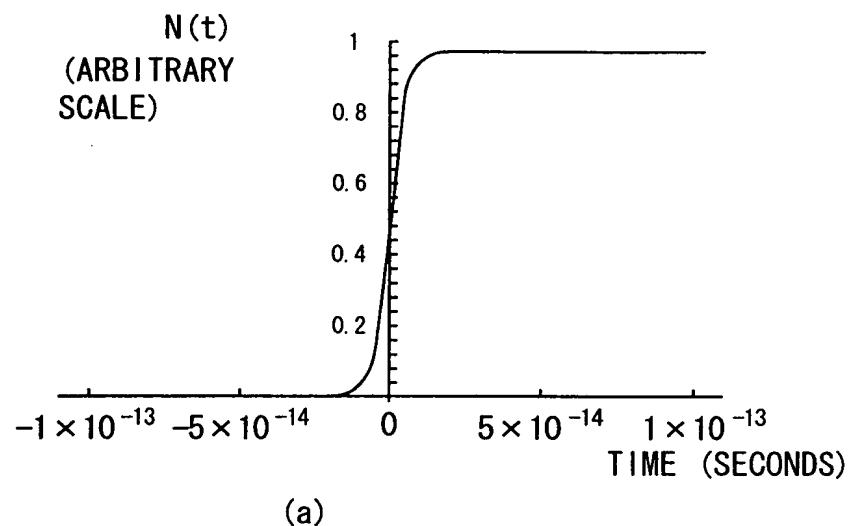
【図2】

EMBODIMENT OF DETECTOR OF THE INVENTION



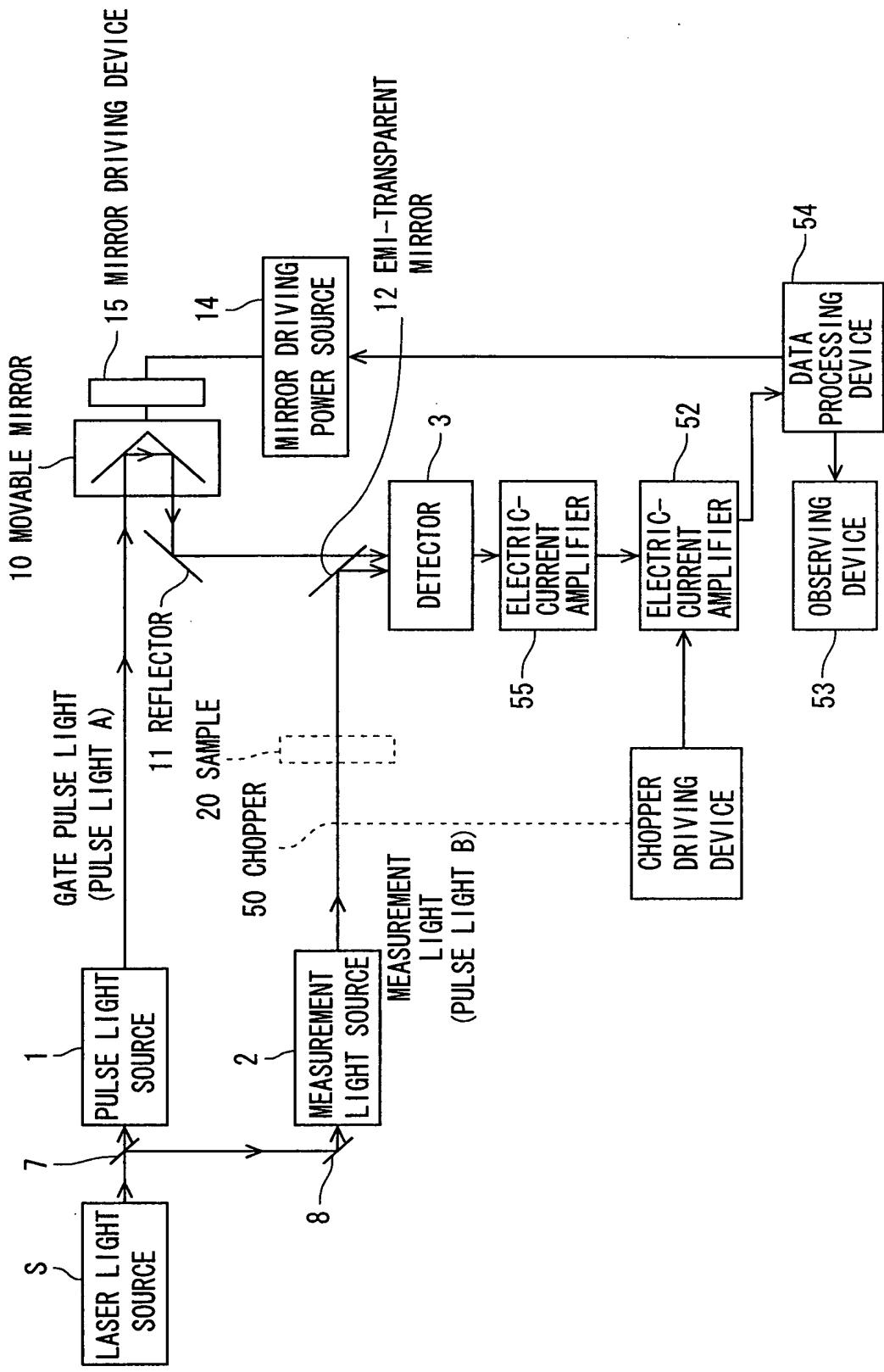
【図3】

EXPLANATION VIEW OF PULSE WIDTH OF GATE PULSE LIGHT FOR REALIZING T



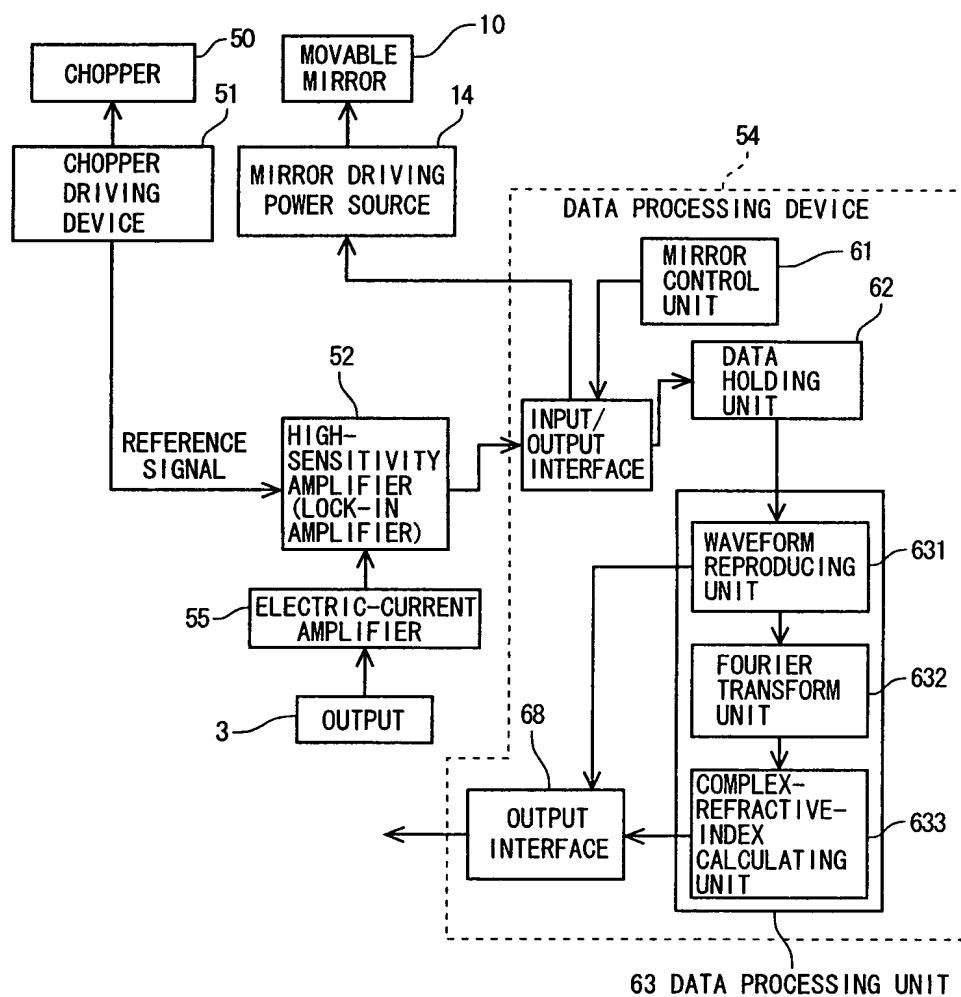
【図4】

SECOND EMBODIMENT OF THE INVENTION



【図5】

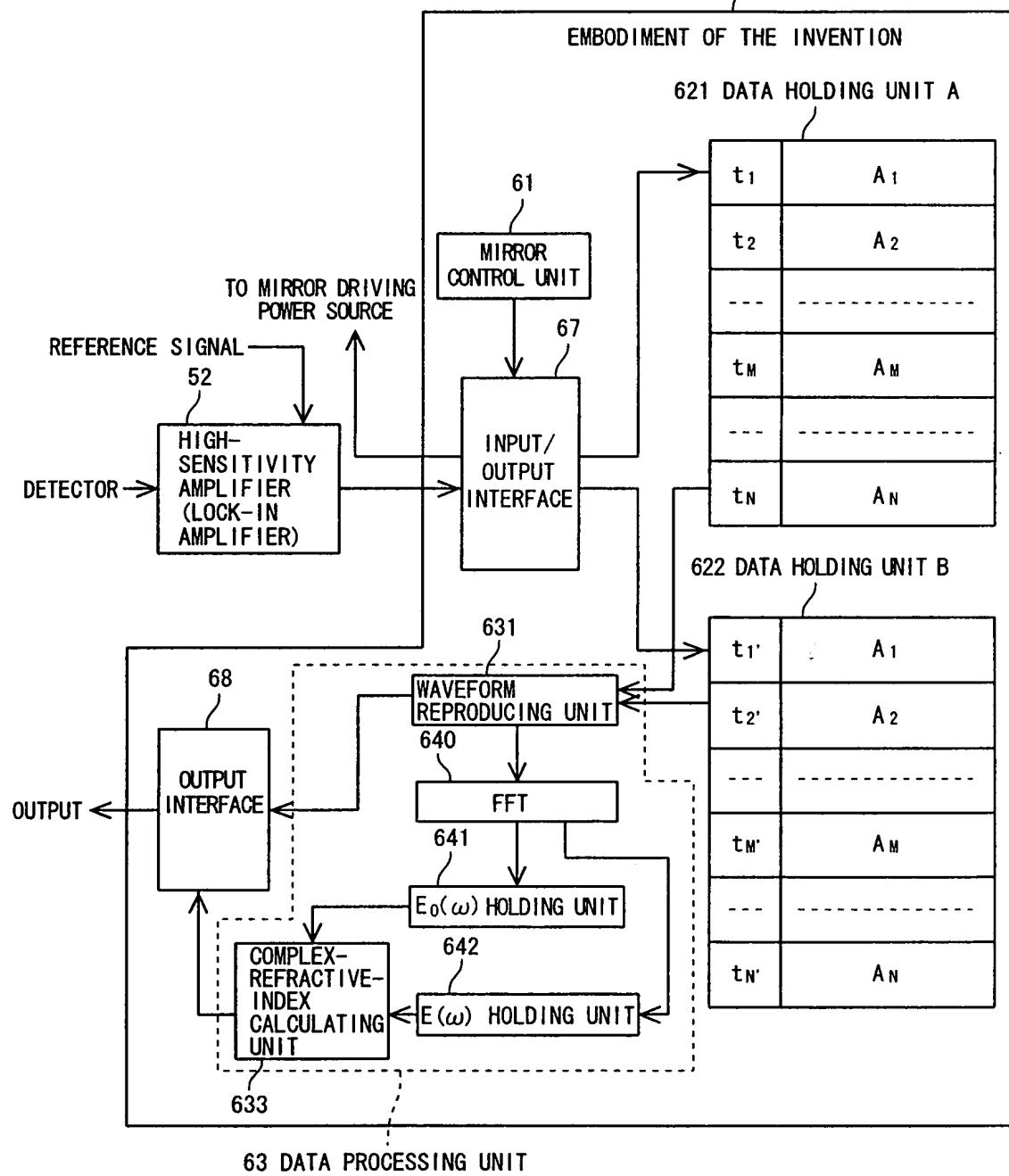
SYSTEM CONFIGURATION ACCORDING TO SECOND EMBODIMENT OF THE INVENTION



【図6】

CONFIGURATION OF DATA PROCESSING DEVICE ACCORDING TO SECOND

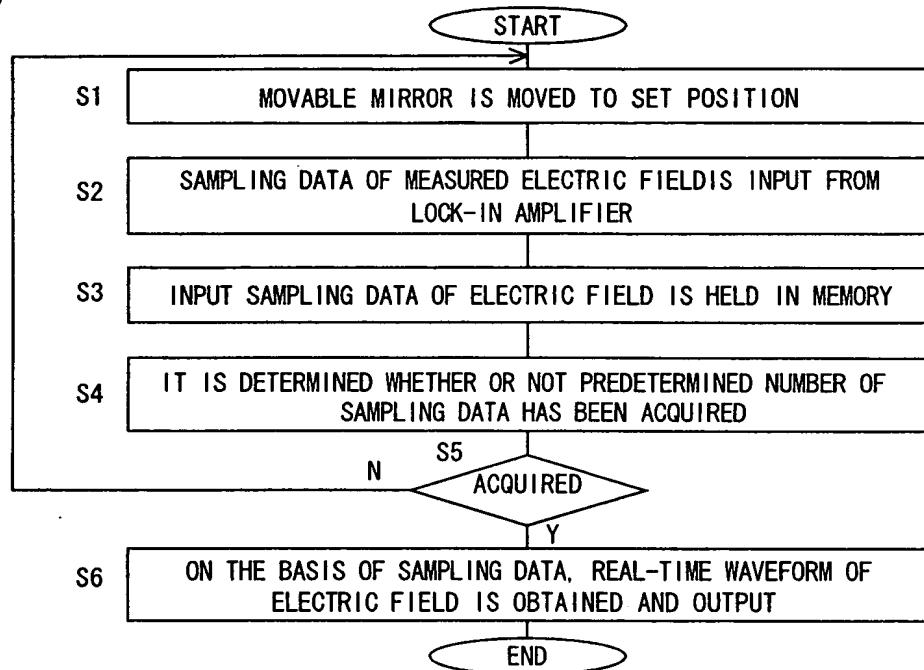
54



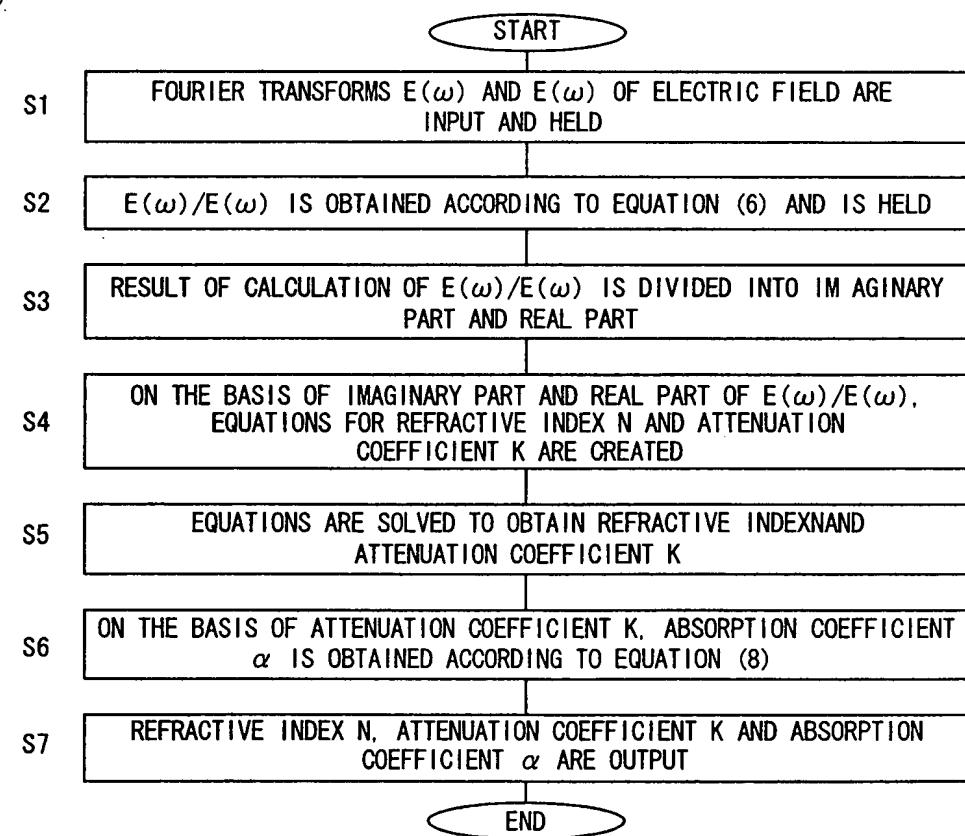
【図7】

FLOW CHART IN DATA PROCESSING DEVICE ACCORDING TO SECOND EMBODIMENT
OF THE INVENTION

(a)

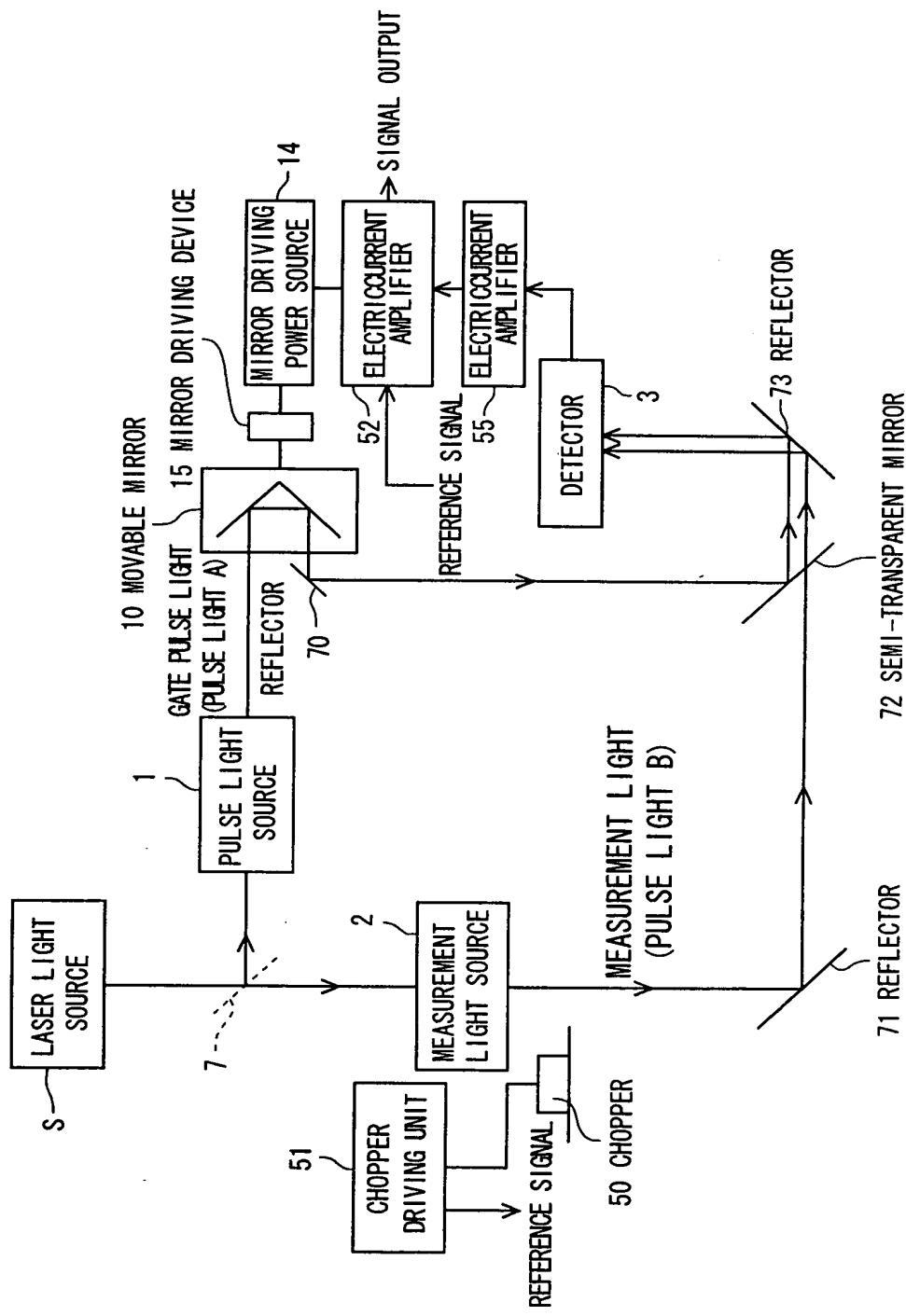


(b)



【図8】

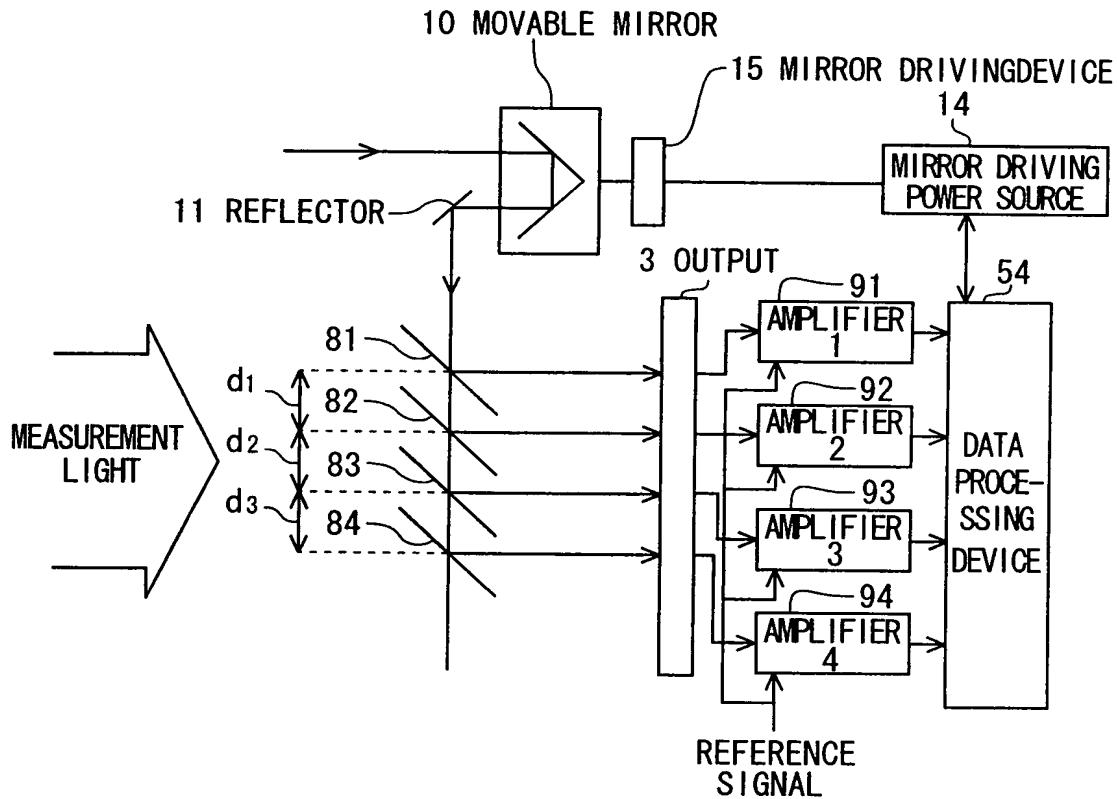
THIRD EMBODIMENT OF THE INVENTION



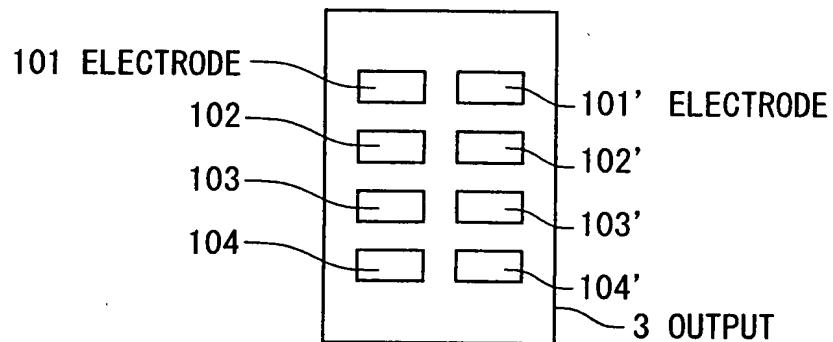
【図9】

FOURTH EMBODIMENT OF THE INVENTION
FIRST METHOD FOR PERFORMING MEASUREMENT FOR PLURAL OPTICAL-PATH
DIFFERENCES THROUGH SINGLE IRRADIATION OF GATE PULSE LIGHT

(a)

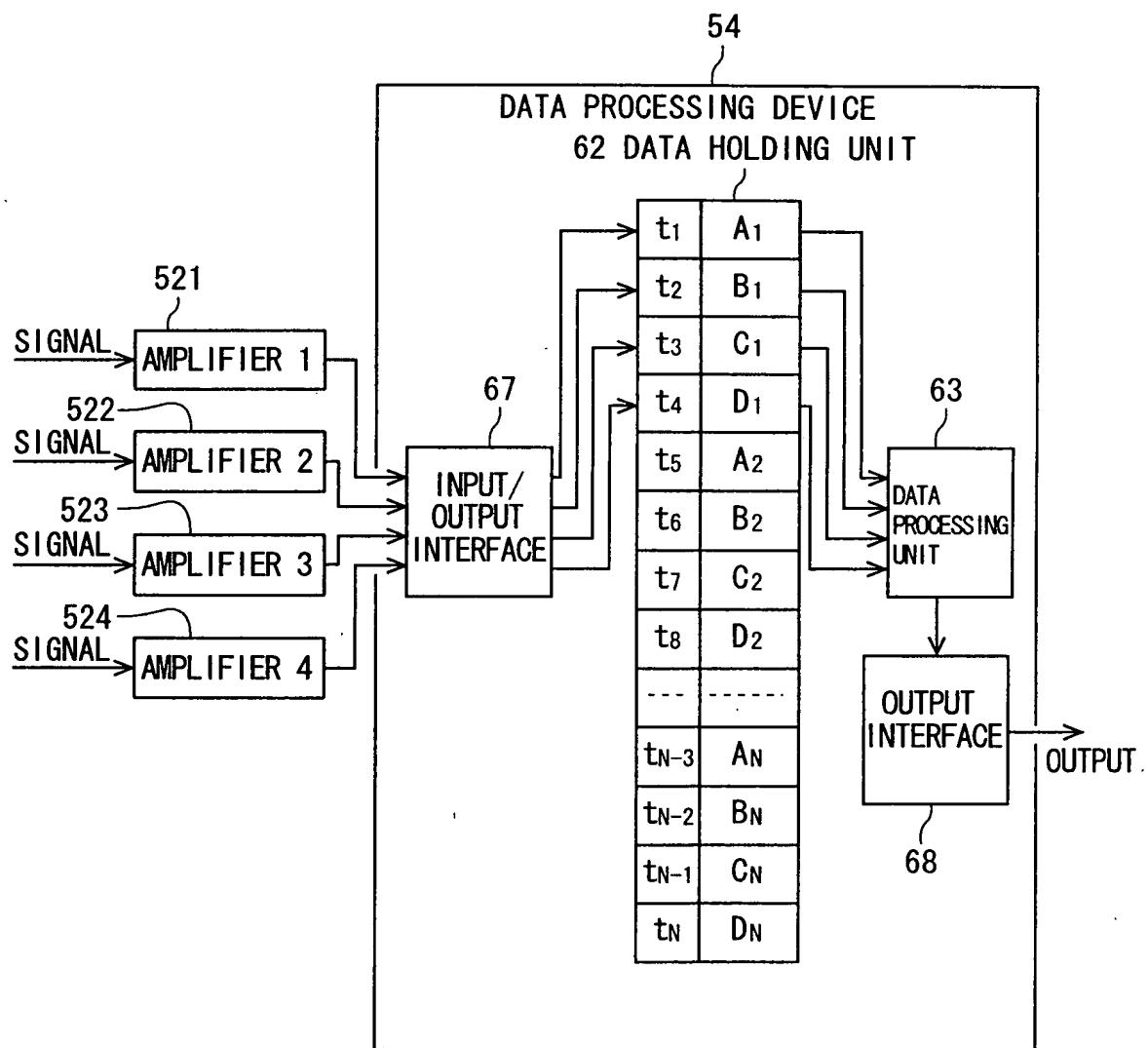


(b)



【図10】

CONFIGURATION OF DATA PROCESSING DEVICE ACCORDING TO FOURTH
EMBODIMENT OF THE INVENTION

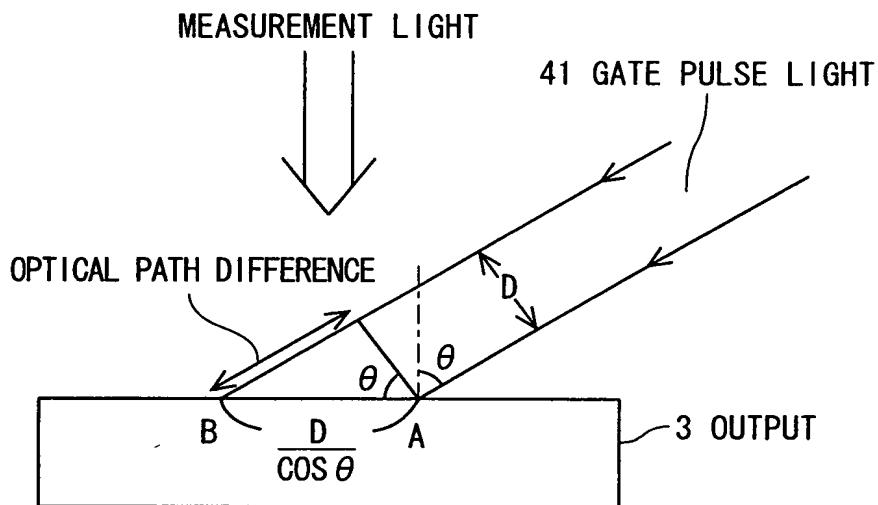


【図11】

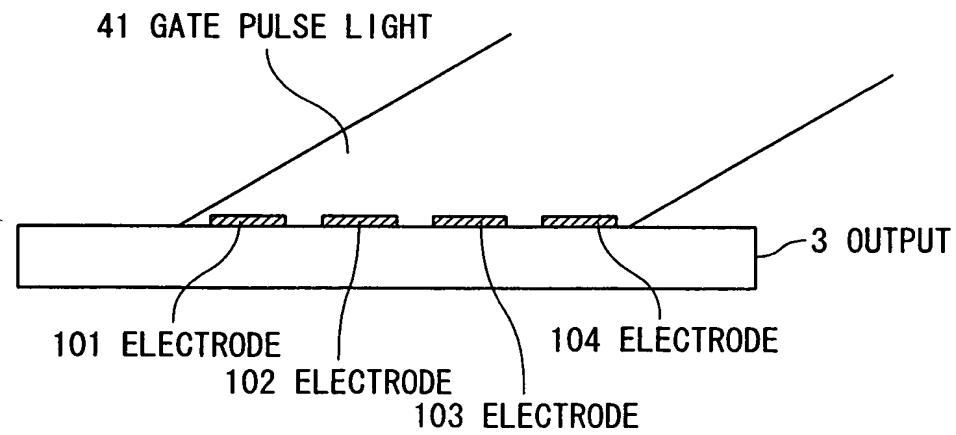
FOURTH EMBODIMENT

(SECOND METHOD FOR PERFORMING MEASUREMENT FOR PLURAL OPTICAL-PATH DIFFERENCES THROUGH SINGLE IRRADIATION OF GATE PULSE)

(a)

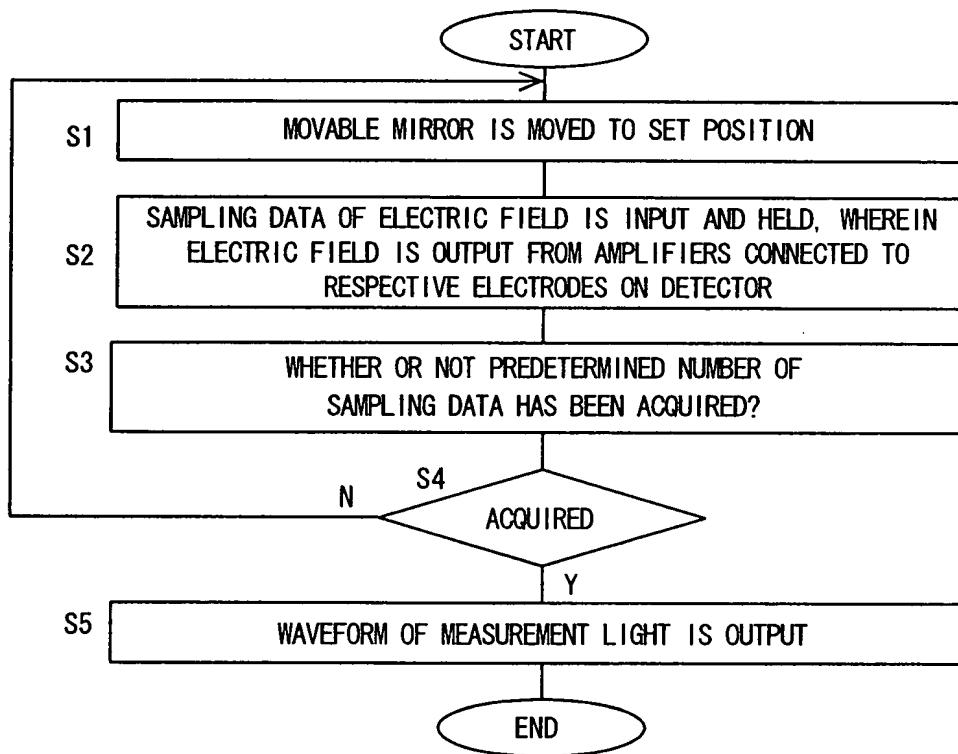


(b)



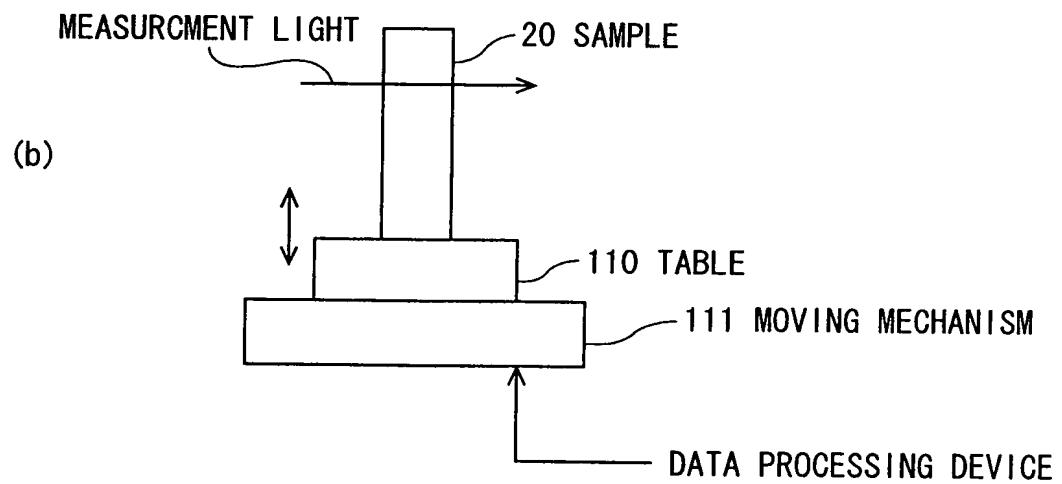
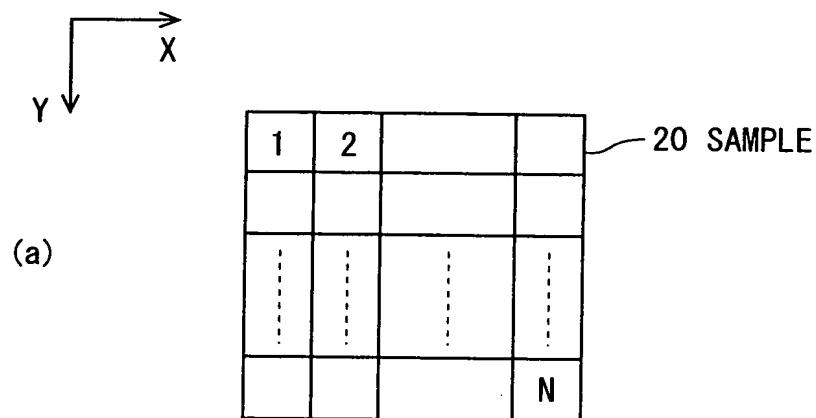
【図12】

FLOW CHART IN DATA PROCESSING DEVICE ACCORDING TO FOURTH EMBODIMENT
OF THE INVENTION



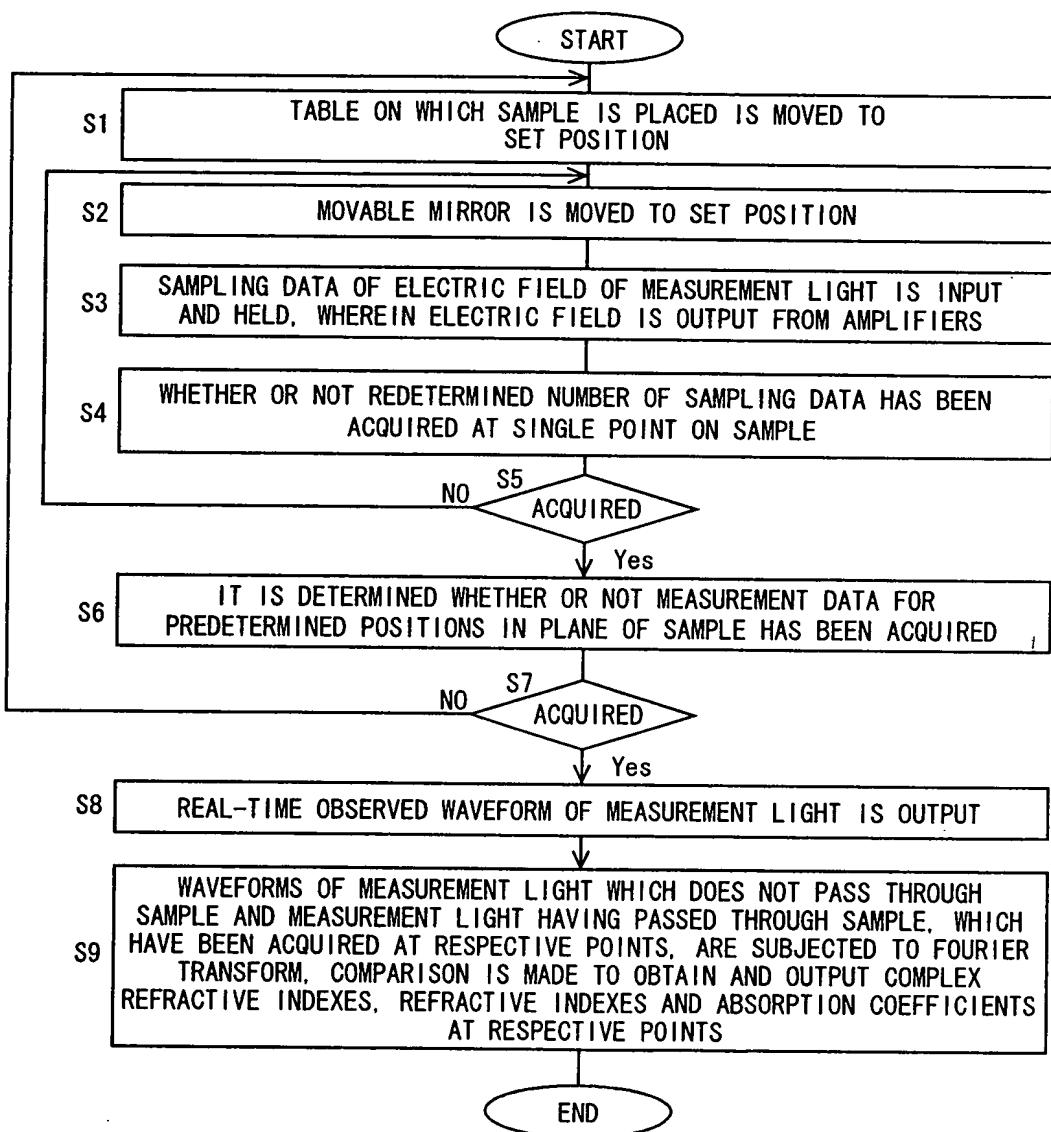
【図13】

FIFTH EMBODIMENT

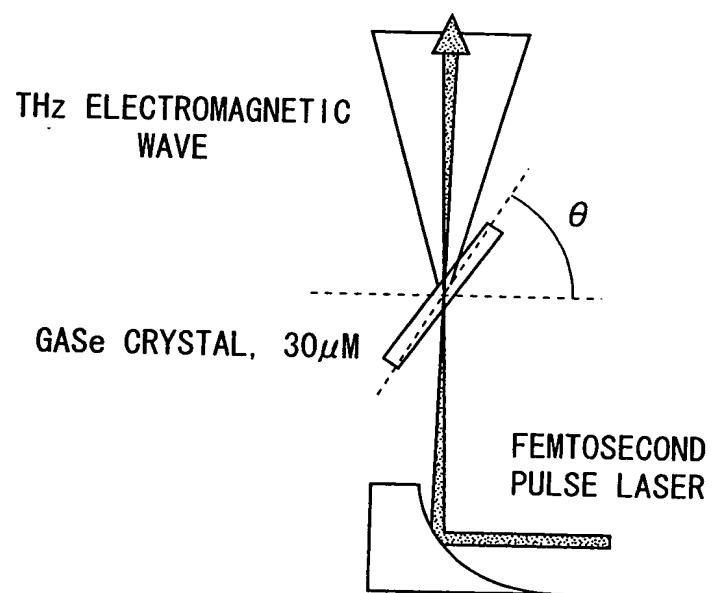


【図14】

FLOW CHART IN DATA PROCESSING DEVICE ACCORDING TO FIFTH EMBODIMENT OF THE INVENTION

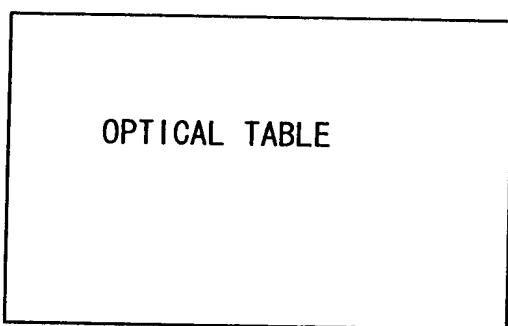
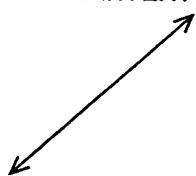


【図15】

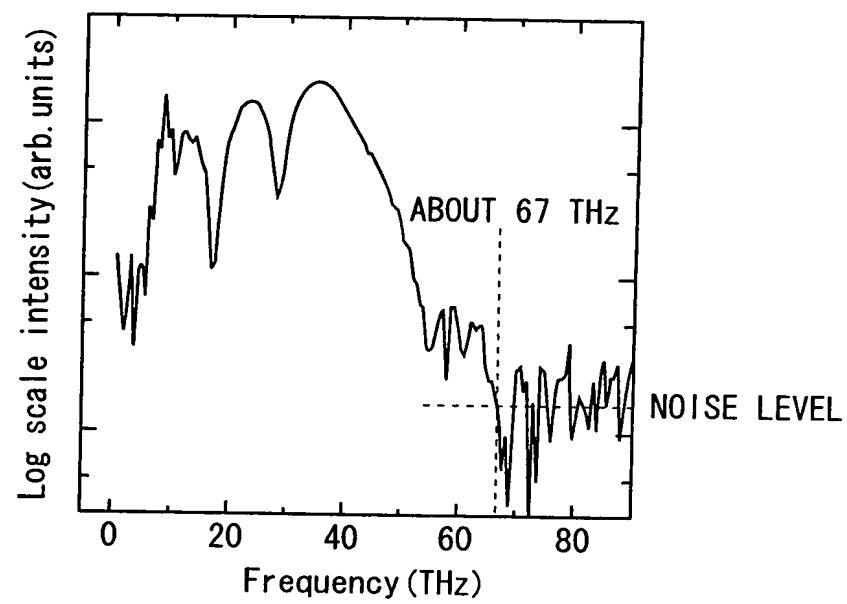


【図16】

DIRECTION OF POLARIZATION OF PULSE LIGHT

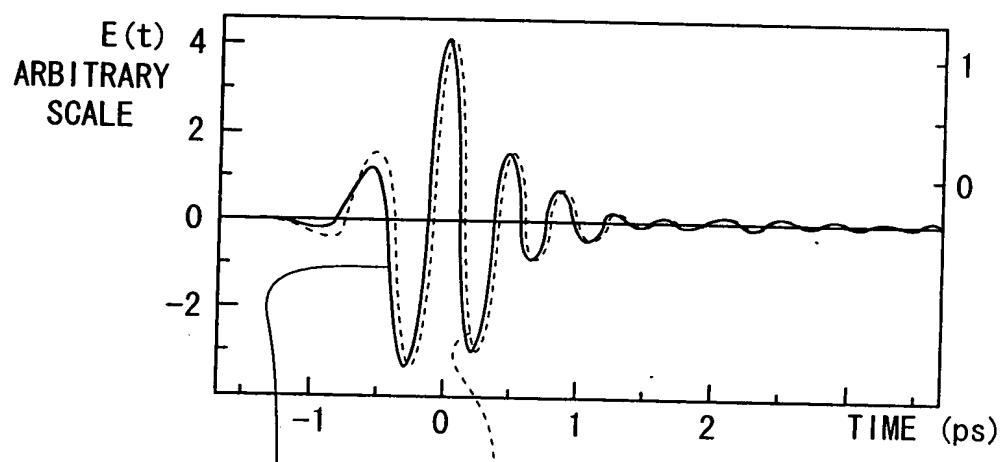


【図17】



【図18】

EXPLANATION VIEW OF MEANS FOR SOLVING PROBLEMS



MEASUREMENT LIGHT HAVING
PASSED THROUGH SAMPLE

MEASUREMENT LIGHT WHICH
DOES NOT PASS THROUGH SAMPLE